

IN THE CLAIMS:

Please amend the claims as follows:

1. **(Currently Amended)** An electrostatic chuck comprising:

a substrate;

a dielectric layer formed by thermal spraying on an upper face of the substrate;

an internal electrode embedded in the dielectric layer;

a feeder terminal portion extending from a lower face of the substrate to the internal electrode; and

an electrode provided in the feeder terminal portion,

wherein the feeder terminal portion is composed of members which are fixed to each other by brazing, diffusion bonding, or soldering, and wherein the feeder terminal portion and the substrate are fixed to each other by mechanical joining.

2. **(Original)** The electrostatic chuck according to claim 1, wherein the feeder terminal portion is structured so as to be removably mounted to the substrate.

Claim 3 **(Canceled).**

4. **(Original)** The electrostatic chuck according to claim 1, wherein the electrode provided in the feeder terminal portion is made of an elastic body.

5. **(Currently Amended)** A production method for an electrostatic chuck comprising steps of:

forming a first dielectric layer by thermal spraying on an upper face of a substrate;

providing a part of an electrode and a jig on the substrate;

forming an internal electrode by thermal spraying on an upper face of the part of an electrode, the jig and the first dielectric layer,

forming a second dielectric layer by thermal spraying on an upper face of the internal electrode;

removing the jig from the substrate; and

mounting a feeder terminal portion to the substrate by mechanical joining,

wherein members of the feeder terminal portion are fixed to each other by brazing, diffusion bonding, or soldering beforehand.

6. **(Original)** The production method for an electrostatic chuck according to claim 5, wherein the feeder terminal portion is structured so as to be removably mounted to the substrate.

Claim 7 **(Canceled).**

8. **(Original)** The production method for an electrostatic chuck according to claim 5, wherein the electrode provided in the feeder terminal portion is made of an elastic body.

9. **(New)** The electrostatic chuck according to claim 1, wherein the dielectric layer has a recess formed thereon, the internal electrode has an exposed portion which is exposed to the feeder terminal portion in the recess, the electrode being provided at the exposed portion of the internal electrode in the recess so as to be apart from the dielectric layer and project from the recess to the feeder terminal portion.

10. **(New)** The production method for an electrostatic chuck according to claim 5, wherein a recess is formed on the first dielectric layer, a portion of the internal electrode is exposed portion which is exposed to the feeder terminal portion in the recess, the electrode being provided at the exposed portion of the internal electrode in the recess so as to be apart from the dielectric layer and project from the recess to the feeder terminal portion.